

Fabrice Iacovella, Ph.D.

Personal Details	Born in France, April 12th 1988 Nationality: French Marital status: Single
Working address	Microelectronics Research Group (MRG) Institute of Electronic Structure and Laser (IESL) Foundation for Research and Technology (FORTH) 1 st Floor, Physics Building, Univ. of Crete 70013, Vassilika Vouton, Herakleion, Crete, Greece Tel: +302810394112 Fax: +302810394105
E-mail	ifabrice@physics.uoc.gr
Education	
March 2014	Ph.D in <i>Nano-physics, nano-devices, nano-measurements</i> Thesis on “ <i>Electronic properties of quasi two-dimensional systems composed of few atomic layers under very intense magnetic field</i> ” Laboratoire National des Champs Magnétiques Intenses, Toulouse, France
Dec 2011	M.Sc in <i>Fundamental Physics</i> , Thesis on “ <i>Electronic properties of graphene under very intense magnetic field and low temperature</i> ” Dpt. of Physics, University Toulouse III, France
July 2009	B.Sc in <i>Fundamental Physics</i> , Dpt. of Physics, University Toulouse III, France
Research Interests	<ul style="list-style-type: none">• Graphene ballistic devices• 2 dimensional transition metal dichalcogenide growth by Chemical Vapor Deposition (CVD) method• 2 dimensional transition metal dichalcogenide electronics• Novel devices for telecommunications and high speed (THz) electronics
Work experience	
2017 – today	<ul style="list-style-type: none">• Postdoctoral fellow<ul style="list-style-type: none">◦ FORTH – IESL, Microelectronics Research Group, Herakleion, Greece<ul style="list-style-type: none">▪ Growth of graphene by chemical vapor deposition on metallic thin films▪ Growth of molybdenum disulfide (MoS₂) monolayer by chemical vapor deposition▪ Conception and characterization of MoS₂ FETs
2014 – 2016	<ul style="list-style-type: none">• Postdoctoral Fellow<ul style="list-style-type: none">◦ Crete Center for Quantum Complexity and Nanotechnology (CCQCN), University of Crete (Greece)<ul style="list-style-type: none">▪ Growth of graphene by chemical vapor deposition on metallic thin films▪ Graphene and other 2D material electronics

- Design and characterization of Radio Frequency graphene devices
- Design and characterization of MoS₂ photodetectors

Experience & skills

- Experience in clean room activities (especially for optical and e-beam lithography, metal deposition, lift-off)
- Experience in micro-alignment of graphene flakes (transferring graphene upon boron nitride flakes)
- Experience with cryogenics (4He and 3He cryostats)
- Low-noise transport measurements under high (pulsed) magnetic field
- Experience in growth of graphene and MoS₂ by chemical vapor deposition method
- Electrical characterization of 2D materials transistors at Radio Frequencies
- Expertise in characterization of 2D materials by Raman spectroscopy

Languages *

**(Common European Framework of Reference for Languages)*

	Understanding		Speaking		Writing
	Listening	Reading	Spoken Interaction	Spoken production	
French	Native speaker				
English	Proficient (C2)	Proficient (C2)	Proficient (C2)	Proficient (C2)	Proficient (C2)
Greek	Independent user (B2)	Independent user (B2)	Independent user (B2)	Independent user (B2)	Independent user (B2)
Romanian	Independent user (B1)	Independent user (B1)	Independent user (B1)	Independent user (B1)	Independent user (B1)
Italian	Basic user (A2)	Basic user (A2)	Basic user (A2)	Basic user (A2)	Basic user (A2)
German	Basic user (A2)	Basic user (A2)	Basic user (A2)	Basic user (A2)	Basic user (A2)